

AMENDMENTS TO THE CLAIMS:

1. (Currently Amended) A remote control system for one or more semiconductor manufacturing apparatuses comprising:
 - a supervisory device which controls said one or more semiconductor manufacturing apparatuses; and
 - a remote operation device that accesses said supervisory device through a communication line,
 - wherein upon accessing said supervisory device, said remote operation device displays a same screen as that displayed by said supervisory device, and enables said remote device to perform a same operation as that carried out by said supervisory device on said one or more semiconductor manufacturing apparatuses, and
 - wherein said remote operation device replaces operation parameter files of said supervisory device through remote control.
2. (Previously Presented) The remote control system for one or more semiconductor manufacturing apparatuses according to claim 1, wherein said supervisory device performs user authentication when said remote operation device accesses said supervisory device.
3. (Previously Presented) The remote control system for one or more semiconductor manufacturing apparatuses according to claim 1, wherein upon accessing said supervisory device, said remote operation device simultaneously displays the same screen as that displayed in the said supervisory device.
4. (Previously Presented) The remote control system for one or more semiconductor manufacturing apparatuses according to claim 1, wherein said supervisory device includes an IP routing function for achieving remote control operation from said remote operation device.

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5. (Currently Amended) A remote control system for one or more semiconductor manufacturing apparatuses comprising:

a host device operably connected to said one or more semiconductor manufacturing apparatuses; and

a remote operation device including a communication element that accesses said host device by way of a communication line;

wherein said host device is provided with an IP routing function for achieving remote control operation from said remote operation device, and a communication element having a call incoming function for receiving a call incoming from said communication line, and

said host device performs user authentication when said remote operation device connects to said host device,

wherein, upon authentication, said remote operation device simultaneously displays a same screen as that displayed on said host device, permitting said remote operation device to remotely control and operate said host device,

wherein said remote operation device replaces operation parameter files of said host device through remote control.

6. (Previously Presented) The remote control system for one or more semiconductor manufacturing apparatuses according to claim 5, wherein said host device and said remote operation device each have a modem as said communication element for enabling connection between said host device and said remote operation device through one of an analog line and an analog network.

7. (Previously Presented) The remote control system for one or more semiconductor manufacturing apparatuses according to claim 5, wherein said host device and said remote operation device each have a terminal adapter as said communication element for enabling connection between said host device and said remote operation device through one of an ISDN line and a network.

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8. (Currently Amended) A remote control system for one or more semiconductor manufacturing apparatuses comprising:

a local area network system comprising a plurality of host devices each connected with one or more semiconductor manufacturing apparatuses, and a router connected with said host devices; and

a remote operation device including a router that accesses said host devices by way of a communication line;

wherein said host devices are each provided with an IP routing function for achieving remote control operation from said remote operation device, and a communication element having a call incoming function for receiving a call incoming from said communication line, and

said host devices each perform user authentication when said remote operation device connects to said host devices, so that said remote operation device thus authenticated can individually simultaneously display a same screen as that displayed on each of said host devices, permitting said remote operation device to remotely control and operate said host devices,

wherein said remote operation device thus authenticated replaces operation parameter files of said host devices through remote control.

9. (Original) The remote control system for one or more semiconductor manufacturing apparatuses according to claim 8, wherein said communication line connecting between said host devices and said remote operation device comprises the Internet.

10. (Previously Presented) The remote control system for one or more semiconductor manufacturing apparatuses according to claim 8, wherein said communication line connecting between said host devices and said remote operation device comprises one of a local area network and a wide area network.

11. (Currently Amended) A remote control system for one or more semiconductor

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manufacturing apparatuses comprising:

a local area network system comprising a plurality of host devices each connected with at least one semiconductor manufacturing apparatus, and an access server connected with said host devices; and

a plurality of remote operation devices each having a communication element accessible to said host devices by way of a communication network;

wherein said host devices are each provided with an IP routing function for achieving remote control operation from each of said remote operation devices, and

said host devices each perform user authentication when each of said remote operation devices connects to said host devices,

wherein each of said remote operation devices thus authenticated can individually simultaneously display a same screen as that displayed on each of said host devices, permitting said remote operation devices to remotely control and operate said host devices,

wherein each of said remote operation devices thus authenticated replaces operation parameter files of each of said host devices through remote control.

12. (Previously Presented) The remote control system for one or more semiconductor manufacturing apparatuses according to claim 11, wherein said communication network connecting between said host devices and said remote operation devices comprises at least one of a public telephone network, an ISDN network, the Internet, a local area network and a wide area network.

13. (Previously Presented) The remote control system for one or more semiconductor manufacturing apparatuses according to claim 5, wherein said remote operation device enables same operations as those carried out by said host device.

14. (Previously Presented) The remote control system for one or more semiconductor manufacturing apparatuses according to claim 8, wherein said remote operation device enables same operations as those carried out by said host devices.

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15. (Previously Presented) The remote control system for one or more semiconductor manufacturing apparatuses according to claim 11, wherein each of said remote operation devices enables same operations as those carried out by said host devices.

16. (New) The remote control system for one or more semiconductor manufacturing apparatuses according to claim 1, further comprising a display screen associated with the supervisory device and a display screen associated with the remote operation device.

17. (New) The remote control system for one or more semiconductor manufacturing apparatuses according to claim 5, further comprising a display screen associated with the host device and a display screen associated with the remote operation device.

18. (New) The remote control system for one or more semiconductor manufacturing apparatuses according to claim 8, further comprising a display screen associated with the host device and a display screen associated with the remote operation device.

19. (New) The remote control system for one or more semiconductor manufacturing apparatuses according to claim 11, further comprising a display screen associated with the host device and a display screen associated with the remote operation device.